

Title (en)

METHOD OF DEPOSING SILICON CRYSTALS

Publication

EP 0348608 B1 19920916 (DE)

Application

EP 89105763 A 19890401

Priority

DE 3822169 A 19880630

Abstract (en)

[origin: EP0348608A1] A method is described of exposing silicon crystals on fine-machined, preferably honed surfaces of workpieces made from silicon alloys or from hypereutectic aluminium-silicon alloys such as Al Si 17 Cu 4 Mg, in which the silicon crystals (1) are embedded in a substantially softer matrix (2). To this end, the surface of the workpiece is treated with a brush (4 to 30) subsequently to the fine machining.
<IMAGE>

IPC 1-7

B24B 33/02; B24D 13/10

IPC 8 full level

B24B 33/02 (2006.01); **B24D 13/10** (2006.01)

CPC (source: EP)

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Cited by

DE10163970B4; EP0818271A1; DE102007028294B4; DE10119337C1; DE19956306B4; DE19956306A1; WO9411155A1

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